

Letters

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Gas rarefaction effects during high power pulsed magnetron sputtering of groups IVb and VIb transition metals in Ar

Grzegorz Greczynski, Igor Zhirkov, Ivan Petrov, J. E. Greene more...

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Experimental and computational studies on toughness enhancement in Ti-Al-Ta-N quaternaries

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Jindřich Musil, and Martin Jaroš

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Uniform sputter deposition of high-quality epitaxial complex oxide thin films

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Ivan A. Starkov, Ilya A. Nyapshaev, Alexander S. Starkov, Sergey N. Abolmasov more...

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V. S. Santosh K. Kondeti, Urvashi Gangal, Shurik Yatom, and Peter J. Bruggeman

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Alexandru Marin, Cristian P. Lungu, and Corneliu Porosnicu

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Characterization of aluminum and titanium nitride films prepared by reactive sputtering under different poisoning conditions of target

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Recrystallization of VO₂ films into (011)-oriented micrometer-sized grains on Al₂O₃(001) in biased reactive sputtering

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Structural defects of GaN deposited on (111) Si with Gd₂O₃-related buffer layers

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Impact of deposition rate, underlayers, and substrates on β -tungsten formation in sputter deposited films

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